WEST Search History

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DATE: Tuesday, March 13, 2007

Hide?	Set Name	Query	Hit Count
		DB=USPT; PLUR=YES; OP=ADJ	
☐	L13	L12 and l9	11
☐	L12	(apparatus or tank) same overflow$3 same ((suply$3 or inlet or feed$3) with (bottom or lower)) same (control or valve)	503
		DB=PGPB,USPT; PLUR=YES; OP=ADJ	
☐	L11	L9 and l7	1
		DB=USPT; PLUR=YES; OP=ADJ	
☐	L10	L9 and l7	1
☐	L9	134/56R,94.1,186,902,18.ccls.	3245
		DB=EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ	
☐	L8	(apparatus or tank) same overflow$3 same ((suply$3 or inlet or feed$3) with (bottom or lower)) same (control or valve) same (semiconductor or substrate or article or wafer)	6
		DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI; PLUR=YES; OP=ADJ	
☐	L7	(apparatus or tank) same overflow$3 same ((suply$3 or inlet or feed$3) with (bottom or lower)) same (control or valve) same (semiconductor or substrate or article or wafer)	171
☐	L6	L5 and ((apparatus or tank) same overflow$3 same ((suply$3 or inlet or feed$3) with (bottom or lower)) same (control or valve))	2
☐	L5	l4 or l3 or l2 or l1	11780
☐	L4	(dainippon screen mfg).as.	11600
☐	L3	nagami-shuzo$.in.	12
☐	L2	ogushi-ryotaro$.in.	1
☐	L1	araki-hiroyuki$.in.	267

END OF SEARCH HISTORY